Author Index for Volume 26

A

Abare, A.C. ..... (3) 325
Abbaschian, L. ..... (11) 1266
Abernathy, C.R. ..... (3) 290, (5) 429, (6) 683, (11) 1266, (11) 1279, (11) 1283, (11) 1287, (11) 1292, (11) 1303, (11) 1314
Abraham, P. ..... (2) L6
Adair, J.H. ..... (11) 1326
Adesida, I. ..... (1) 43, (3) 107, (3) 266, (12) 1376, (12) 1382
Ahmad, I. ..... (3) 144
Ahmed, M.U. ..... (6) 723
Ahn, B.S. ..... (5) 436
Ahrenkiel, S.P. ..... (9) 1048
Akahane, T. ..... (3) 178
Alam, M.R. ..... (11) 1331
Allerman, A.A. ..... (8) 903, (10) 1225
Almeida, L.A. ..... (6) 502
Alok, D. ..... (3) 108, (3) 134
Amirtharaj, P.M. ..... (6) 475
Anderson, E.J. ..... (6) 656
Antonell, M.J. ..... (6) 683, (11) 1283
Apotovsky, B.A. ..... (6) 765
Aqariden, F. ..... (6) 621
Arai, K. ..... (5) 423
Arès, R. ..... (10) 1174
Arias, J.M. ..... (6) 493, (6) 621, (6) 649
Ariel, V. ..... (6) 673
Asa, G. ..... (6) 756
Augustine, F.L. ..... (6) 765
Aulombard, R.L. ..... (3) 294
Auret, F.D. ..... (5) 463
Ayers, J.E. ..... (6) 697, (6) 710

B

Baca, A.G. ..... (9) 1021
Bachem, K.H. ..... (10) 1127
Baek, W.H. ..... (6) 507
Bahir, G. ..... (6) 606, (6) 673
Bahng, J.H. ..... (6) 507
Baik, H.K. ..... (2) 83, (3) 172
Bajaj, J. ..... (6) 649
Bajaj, K.K. ..... (4) 347
Bakru, H. ..... (8) 949
Baliga, B.J. ..... (3) 108, (3) 134
Ballantyne, J.M. ..... (10) 1199
Barbarin, F. ..... (2) L6
Barber, H.B. ..... (6) 765
Barklie, R.C. ..... (3) 137
Barmak, K. ..... (9) 1009, (11) 1370
Barnes, S.L. ..... (6) 482
Barnett, S.A. ..... (9) 1030
Barrett, H.H. ..... (6) 765
Barthe, F. ..... (5) L9
Bartholomew, D.U. ..... (6) 678
Bartoli, E.J. ..... (5) 440
Battaile, C.C. ..... (9) 960
Baucom, K.C. ..... (10) 1178
Baumgratz, B.A. ..... (6) 488
Beaudoin, M. ..... (12) L25
Beccard, R. ..... (10) 1123
Beck, K.M. ..... (11) 1335
Behres, A. ..... (10) 1221
Benz, R. ..... (6) 524
Berding, M.A. ..... (6) 625, (6) 683
Best, A. ..... (6) 643
Bevan, M.J. ..... (6) 502
Bharatan, S. ..... (11) 1361
Bhaskaran, M. ..... (3) 198
Bhat, I.B. ..... (3) 281, (6) 475
Bhat, R. ..... (10) 1097
Bi, W.G. ..... (3) 252
Biasiol, G. ..... (10) 1194
Bicknell-Tassius, R.N. ..... (6) 524
Biefeld, R.M. ..... (1) 37, (8) 903, (10) 1178, (10) 1225
Bishop, S.G. ..... (1) 43, (3) 306
Bleuse, J. ..... (6) 667
Bonnefoy, J.P. ..... (6) 738
Bougrioua, Z. ..... (10) 1205
Breiland, W.G. ..... (1) 37, (10) 1178
Bremser, M.D. ..... (3) 224, (3) 301
Brennan, T.M. ..... (1) 37
Bridges, A.S. ..... (10) 1131
Briner, B.G. ..... (11) 1342
Brinkman, A.W. ..... (6) 610
Briot, O. ..... (3) 294
Brockt, G. ..... (10) 1103, (10) 1221
Brown, A. ..... (6) 723
Bruschi, P. ..... (8) L17
Bubulac, L.O. ..... (6) 649, (6) 656
Buchwalter, L.P. ..... (7) 791
Buczkowski, S.L. ..... (6) 534
Burkhart, J.H. ..... (10) 1225
Butler, J.E. ..... (9) 960, (11) 1320
Byun, D. ..... (10) 1098

C

Caballero, J.A. ..... (11) 1274
Cabbibo, A. ..... (11) 1274
Cabral, C., Jr. ..... (9) 1090
Cahen, D. ..... (2) 97, (8) 893
Cammarata, R.C. ..... (9) 966
Caneau, C. ..... (10) 1097
Cao, J. ..... (1) 1
Capano, M.A. ..... (4) 391
Carasso, M.L. ..... (11) 1326
Carolan, J.F. ..... (2) 73
Carter, C., Jr. ..... (3) 128, (3) 151
Cartujo, P. ..... (3) 203
Case, F.C. ..... (6) 482
Castro, F. ..... (4) 372
Cavus, A. ..... (6) 511
Celii, F. G. ..... (4) 366, (9) 1083
Chaichimansour, M. ..... (6) 728
Chan, Y.C. ..... (1) 21, (4) 387, (5) 470
Chang, J.M. ..... (6) 552
Chang, K.H. ..... (1) 37
Chang, P.C. ..... (5) 440
Chang, Y.C. ..... (12) 1376, (12) 1382
Chapman, G.R. ..... (6) 488
Chason, E.H. ..... (9) 959, (9) 969
Chaudhuri, J. ..... (12) 1389
Chen, A.-B. ..... (6) 571
Chen, A.C. ..... (6) 493
Chen, F. ..... (12) 1371
Chen, H. ..... (1) 43, (8) 944, (12) 1376, (12) 1382
Chen, H.-H. ..... (12) 1401
Chen, H.S. ..... (8) 954
Chen, J. ..... (11) 1361
Chen, J.C. ..... (3) 330, (4) 361
Chen, K. ..... (4) 397
Chen, K.M. ..... (9) 1039
Chen, Q. ..... (3) 266
Chen, Y. ..... (4) 350, (10) 1184
Chen, Z. ..... (9) 1076
Cheng, K.Y. ..... (12) 1382
Cheng, W.H. ..... (8) 889, (8) L21
Cheng, X. ..... (12) 1389
Cheong, H.M. ..... (9) 1048
Cherukuri, K.C. ..... (12) 1422
Chi, P.H. ..... (3) 144, (3) 334
Chi, S. ..... (8) L21
Childress, J.R. ..... (11) 1274, (11) 1310
Chin, J. ..... (7) 783
Chiu, D.S. ..... (4) 387, (5) 470
Cho, M.W. ..... (5) 423
Choi, H.K. ..... (10) 1231
Choi, J.B. ..... (6) 584
Choi, K.K. ..... (6) 552
Choi, W.C. ..... (5) 436
Choutov, D.A. ..... (3) 301
Chow, P.C. ..... (11) 1266, (11) 1292
Chowdhury-Nagle, S. ..... (4) 347
Chu, A.K. ..... (8) 889
Chu, R. ..... (9) 1083
Chua, S.J. ..... (9) 1070
Chuang, S.L. ..... (1) 43, (12) 1376, (12) 1382
Chui, H.C. ..... (1) 37
Chun, Y.S. ..... (10) 1250
Chung, D.D.L. ..... (8) 928
Chung, H. ..... (6) 515
Chung, U.I. ..... (2) L1
Ciofi, C. ..... (8) L17
Clark, J.C. ..... (6) 610
Clarke, F.W. ..... (6) 593
Clarke, R. ..... (11) 1265
Clevenger, L.A. ..... (9) 1090
Cochrane, J.W. ..... (8) 915
Cocoziello, A. ..... (8) 949
Cohen, P.I. ..... (3) 272
Coldren, L.A. ..... (3) 325
Coleman, J.J. ..... (3) 306, (10) 1164
Colin, T. ..... (6) 688
Collins, M. ..... (3) 137
Colter, P.C. ..... (10) 1145
Conrad, H. ..... (7) 774
Constantine, C. ..... (11) 1303
Contessa, C.M. ..... (8) 922
Cooper, D.E. ..... (6) 649
Cooper, J.A., Jr. ..... (3) 208
Crawford, D.E. ..... (3) 272
Crawford, M.H. ..... (10) 1140
Cuomo, J.J. ..... (11) 1270
Curtis, A.P. ..... (1) 43, (12) 1376, (12) 1382
Curtis, T.J. ..... (11) 1297

D

D'Souza, A.I. ..... (6) 649, (6) 656
Dabiran, A.M. ..... (3) 272
Dahleh, M.A. ..... (10) 1145

Dapkus, P.D. ..... (10) 1114
Dashell, M.D. ..... (12) 1371
Dattilo, V. ..... (8) L17
Davidson, M.R. ..... (11) 1355
Davis, R.F. ..... (3) 224, (3) 301
Dawson, L.C. ..... (6) 656
DeCorby, R.G. ..... (12) L25
DeLong, M.C. ..... (7) 878
DeLyon, T.J. ..... (6) 488
Demangeot, F. ..... (3) 294
Demkowicz, P.A. ..... (11) 1326
DenBaars, S.P. ..... (3) 325, (10) 1118
Denhoff, M.W. ..... (8) 941
DePinto, G. ..... (4) 376
Dereniak, E.L. ..... (6) 765
Derr, J.W. ..... (6) 656
Desjardins, P. ..... (10) 1205
Desrosiers, R.M. ..... (3) 237
Devrajan, J. ..... (3) 217
DeWames, R.E. ..... (6) 649
DiFilippo, V. ..... (7) 847
Diligenti, A. ..... (8) L17
Dixit, G. ..... (9) 987
Donovan, S.M. .. (11) 1266, (11) 1292
Dosanjh, P. ..... (2) 73
Doty, F.P. ..... (6) 765
Dow, J.D. ..... (4) 341
Drews, M. ..... (4) 402
Dudley, M. .. (3) 128, (3) 151, (6) 515
Dugay, M. ..... (2) L6
Duncan, W.M. ..... (6) 502
Dunnigan, S. ..... (4) 376
Dupuis, R.D. ..... (3) 257

E

Eastman, L. ..... (1) 30
Eddy, C.R., Jr. ..... (11) 1320
Edgar, J.H. ..... (12) 1389
Edwall, D.D. ..... (6) 493, (6) 621, (6) 649, (6) 656
Edwards, A. ..... (3) 334
Eichel-Streiber, C.V. ..... (10) 1221
Eiting, C.J. ..... (3) 257
Eliseev, P.G. ..... (3) 311
Elliott, C.T. ..... (6) 643
Eskin, J.D. ..... (6) 765
Evwaraye, A.O. ..... (3) 113
Eyink, K.G. ..... (4) 391

F

Fach, A. ..... (7) 873
Fang, W. (1) 43, (12) 1376, (12) 1382
Fang, X.M. ..... (5) 444
Fang, Z.-Q. ..... (12) L29
Fawaz, H. ..... (1) 16
Feenstra, R.M. ..... (11) 1342
Fekete, D. ..... (10) 1199
Felix, C.L. ..... (5) 440
Feng, M. (1) 43, (12) 1376, (12) 1382
Field, D.P. ..... (9) 996
Fijol, J.J. ..... (6) 715
Fine, M. ..... (7) 783
Flanders, D.R. ..... (7) 883
Floro, J.A. ..... (9) 969
Follstaedt, D.M. ..... (9) 1048
Forbes, D.V. ..... (10) 1164
Frandon, J. ..... (3) 294
Freund, L.B. ..... (9) 969
Friedmann, T.A. ..... (9) 1021
Furioli, J. ..... (3) 311
Fuyuki, T. ..... (3) 160

G

Gámiz, F. ..... (3) 203
Gan, S. ..... (10) 1189
Gan, Z.-Q. ..... (8) 910
Gao, M. ..... (8) 941
Gao, Y. ..... (6) 588
Garcia, J.P. ..... (6) 765
Gardner, J.A. ..... (3) 144
Gedridge, R.W., Jr. ..... (11) 1283
Gellman, A.J. ..... (10) 1261
Georgieva, A. ..... (3) 119
Gibson, J.M. ..... (1) 43, (12) 1376
Gil, B. ..... (3) 294
Gilbert, D.R. ..... (11) 1326, (11) 1365
Giles, N.C. ..... (6) 732
Gillis, H.P. ..... (3) 301
Giust, G.K. ..... (8) L13
Glass, R. ..... (3) 128
Glasser, F. ..... (6) 738
Glembocki, O.J. ..... (11) 1320
Gluck, N.S. ..... (6) 649
Goel, A. ..... (3) 193
Goetz, P. ..... (6) 476
Goldberg, L. ..... (5) 440
Goldman, R.S. ..... (11) 1342
Goldys, E.M. ..... (8) 922
Gonzalez, J. ..... (12) 1428
Goodman, S.A. ..... (5) 463
Goorsky, M.S. ..... (6) 529
Gordon, N.T. ..... (6) 643
Gorelik, Y. ..... (6) 756
Gouin, F. ..... (12) L25
Govorkov, A.V. ..... (3) 237
Green, L. ..... (10) 1237
Greene, B.J. ..... (6) 567
Greve, D.W. ..... (3) 237
Grizzle, J.W. ..... (12) 1401
Grodzinski, P. ..... (1) 37
Gross, T.S. ..... (7) 773, (7) 791
Grow, J.M. ..... (3) 198
Grudowski, P.A. ..... (3) 257
Guillon, S. ..... (10) 1205
Guillot, C. ..... (2) L6
Gurskii, A.L. ..... (10) 1256
Gustafsson, A. ..... (10) 1194
Gutmann, R.J. ..... (8) 935

H

Ha, J.M. ..... (2) L1
Haas, T.W. ..... (4) 391
Hacke, P.L. ..... (7) 774
Hadji, E. ..... (6) 667
Haggag, F.M. ..... (7) 839
Hahn, M.S. ..... (6) 584
Hahn, Y.-B. ..... (12) 1394
Hairston, A. ..... (6) 482
Hall, R. ..... (6) 649
Hall, R.S. ..... (6) 643
Halliburton, L.E. ..... (6) 732
Hallin, C. ..... (3) 119
Hamadeh, H. ..... (10) 1256
Hamilton, W.J. ..... (6) 765
Hammons, B.E. ..... (1) 37, (10) 1140, (10) 1178
Han, B.K. ..... (10) 1189
Han, M.S. ..... (6) 507
Hanish, C.K. ..... (12) 1401
Hao, P.H. ..... (1) 25
Hardwick, J. ..... (10) 1131
Härle, V. ..... (10) 1103
Harmand, J.C. ..... (5) L9
Harper, B.D. ..... (7) 798, (7) 821
Harper, J.M.E. ..... (9) 1090
Harris, J.S. ..... (8) 898
Harrison, W.A. ..... (7) 878
Hartman, Q. ..... (12) 1376
Harton, T.B. ..... (4) 366
Hartzell, D. ..... (1) 30
Hatayama, T. ..... (3) 160
Hauenstein, R.J. .. (5) 444, (11) 1342
Haynes, T.E. ..... (11) 1283
He, X.-F. ..... (2) 73
Heime, K. ..... (10) 1221
Heinrich, A.J. ..... (4) 383
Held, R. ..... (3) 272
Heller, E. ..... (6) 710
Helms, C.R. . (6) 600, (6) 629, (6) 678
Heremans, J. ..... (10) 1237
Hermon, H. ..... (6) 529
Hersee, S.D. ..... (10) 1109, (10) 1134
Hess, W.P. ..... (11) 1335
Heuken, M. ..... (10) 1221, (10) 1256
Hickman, R.J. ..... (10) 1140
Hicks, R.F. ..... (10) 1169, (10) 1189
Hiraga, K. ..... (3) 232
Hirsch, L.S. ..... (6) 534
Ho, I.H. ..... (10) 1250
Ho, P.S. ..... (7) 805
Hobson, W.S. ..... (5) 429, (11) 1279, (11) 1303, (11) 1314
Hoff, H.A. ..... (2) 90
Hoffman, C.A. ..... (5) 440, (6) 584
Holander-Gleixner, S. ..... (6) 629
Holland, O.W. ..... (3) 144, (3) 334, (11) 1265, (11) 1349
Holloway, P.H. ..... (6) 715, (11) 1355
Holm, B. ..... (3) 137
Holm, R.T. ..... (11) 1320
Holmes, A.L. ..... (3) 257
Holmes, D.S. ..... (12) 1371
Hong, B.Z. ..... (7) 814
Hong, J. ..... (3) 290, (5) 429, (11) 1279, (11) 1303, (11) 1314
Horley, G.A. ..... (10) 1174
Horton, T. ..... (1) 43, (12) 1376, (12) 1382
Hou, H.Q. ..... (10) 1140, (10) 1178
Hou, Y.B. ..... (6) 507, (6) 584
Hsieh, K.C. ..... (1) 43, (12) 1376, (12) 1382
Hsieh, K.C. ..... (8) L21
Hsu, T.C. ..... (10) 1250
Hsu, Y. ..... (10) 1244, (10) 1250
Huang, Z.C. ..... (3) 330
Huang, Z.C. ..... (4) 361

Hurst, A.T., Jr. ..... (11) 1310
Hwang, C.-Y. ..... (3) 243
Hwang, R.Q. ..... (9) 969

I

Idiart-Alhor, E. ..... (5) L9
Inglefield, C.E. ..... (7) 878
Inoue, M. ..... (3) 165
Inoue, N. ..... (3) 165
Irvine, S.J.C. ..... (6) 723
Isaacs-Smith, T. ..... (3) 212
Isaacson, I.P. ..... (2) 90
Itkin, V.Y. ..... (7) 821
Itoh, A. ..... (3) 165
Ivey, K. ..... (4) 402
Iyer, S. ..... (4) 347

J

Jack, M.D. ..... (6) 488
Jackson, J. ..... (11) 1361
Jackson, S.L. .... (12) 1376, (12) 1382
Jacobs, E.G. ..... (7) 883
Jagadish, C. ..... (5) 449
Jain, F.C. ..... (6) 697, (6) 710
Jamba, D.M. ..... (6) 476
James, R.B. ..... (6) 529
Jandik, J.E. ..... (6) 656
Janzén, E. ..... (3) 119
Jasinski, J. ..... (5) 449
Jennings, G. ..... (6) 750
Jensen, J.E. ..... (6) 476, (6) 488
Jenson, M. ..... (11) 1310
Jeoung, Y.T. ..... (6) 552, (6) 584
Jesson, D.E. ..... (9) 1039
Jimenez-Sandoval, S. ..... (2) 73
Jin, C.G. ..... (6) 705
Jin, S. ..... (8) 954
Jogai, B. ..... (7) 863
John, J. ..... (7) 873
Johnson, B. ..... (6) 488
Johnson, J. ..... (6) 476
Johnson, M.B. ..... (5) 444
Johnson, S.M. ..... (6) 476
Johnston, A.M. ..... (3) 272
Jonczyk, R. ..... (12) 1371
Jones, A.C. ..... (10) 1174
Jones, A.M. ..... (3) 306
Jones, C.L. ..... (6) 643
Jones, E.D. ..... (1) 37, (9) 1048
Jones, E.D. ..... (6) 610
Jones, K.S. ..... (11) 1361
Jones, R.L. ..... (12) L29
Jordan-Sweet, J. ..... (9) 1090
Juergensen, H. ..... (10) 1123
Jung, H. ..... (6) 662
Jung, H.D. ..... (5) 423
Jung, K.B. ..... (11) 1310
Jürgensen, H. ..... (10) 1127

K

Kajihara, N. ..... (6) 616
Kakanakov, R. ..... (3) 119
Kalisch, H. ..... (10) 1256
Kalisetty, S. ..... (6) 697, (6) 710
Kaminska, M. ..... (5) 449
Kamlet, L.I. ..... (12) 1401, (12) 1409
Kammlott, G.W. ..... (8) 954
Kang, T.W. ..... (6) 507, (6) 584
Kang, Y.-S. ..... (7) 805
Kanjolia, R. ..... (4) 361
Kao, Y.C. ..... (9) 1083
Kapon, E. ..... (10) 1194
Kappers, M.J. ... (10) 1169, (10) 1189
Karam, N.H. ..... (6) 745, (10) 1145
Karlicek, R.F. ..... (11) 1287
Kasamakova, L. ..... (3) 119
Kaufmann, U. ..... (10) 1127
Keer, L. ..... (7) 783
Keller, R.C. ..... (6) 542
Keller, R.R. ..... (9) 996
Keller, S. ..... (3) 325, (10) 1118
Kenner, V.H. ..... (7) 798, (7) 821
Khan, M.A. ..... (3) 266
Kheyrandish, H. ..... (6) 723
Kikuma, I. ..... (1) 34
Kim, C.-K. ..... (6) 556, (6) 662
Kim, C.-S. ..... (2) 83
Kim, C.C. ..... (6) 561
Kim, C.W. ..... (4) 355
Kim, D.-W. ..... (2) 83
Kim, E.K. ..... (5) 436
Kim, H.K. ....(6) 507, (6) 552, (6) 584
Kim, H.N. ..... (2) 83
Kim, J.-W. ..... (12) 1394
Kim, J.H. ..... (10) 1250
Kim, J.M. ..... (6) 507, (6) 552, (6) 584
Kim, K. ..... (6) 662
Kim, K.J. ..... (6) 507
Kim, M.-S. ..... (5) 436
Kim, M.H. ..... (1) 37
Kim, S.-I. ..... (5) 436
Kim, S.U. ..... (6) 552
Kim, T.W. ..... (6) 507
Kim, Y. ..... (9) 1002
Kim, Y.D. ..... (10) 1164
Kim, Y.H. ..... (6) 552
Kim, Y.I. ..... (3) 172
Kim, Y.S. ..... (2) L1
Kimoto, T. ..... (3) 165
Kimura, K. ..... (2) 53, (6) 705
King, A.H. ..... (9) 987
King, C.N. ..... (11) 1355
Knauer, A. ..... (10) 1154
Knorr, K. ..... (10) 1159
Ko, D.-H. ..... (2) L1
Kobayashi, J.T. ..... (10) 1114
Kobayashi, N. ..... (10) 1214
Kobayashi, N.P. ..... (10) 1114
Koh, K.A. ..... (9) 1070
Koh, K.W. ..... (5) 423
Koh, Y.B. ..... (2) L1
Kolbas, R.M. ..... (3) 325
Kolodzey, J. ..... (12) 1371
Kong, H.-S. ..... (3) 151
Kosai, K. ..... (6) 476, (6) 488
Kotlicki, A. ..... (2) 73
Kozlowski, L.J. ..... (6) 649
Krishnamoorthy, V. ..... (11) 1283
Krishnamurthy, S. ..... (6) 571
Krishnankutty, S. ..... (3) 325
Krotkus, A. ..... (5) 449
Krusor, B.S. ..... (3) 285
Kučera, M. ..... (1) 7
Kúdela, R. ..... (1) 7
Kuhler, K. ..... (6) 482
Kum, D. ..... (10) 1098
Kumar, A. ..... (11) 1331
Kumar, D. ..... (11) 1265
Kuo, H.C. .. (1) 43, (8) 944, (12) 1376, (12) 1382
Kuo, J.M. ..... (8) 944
Kuo, L.H. ..... (2) 53, (6) 705
Kurpas, P. ..... (10) 1154, (10) 1159
Kurtz, S.R. ..... (8) 903, (10) 1225
Kussmaul, A. ..... (10) 1145
Kvam, E.P. ..... (9) 959
Kwak, J.S. ..... (2) 83, (3) 172

L

Labanda, J.G.C. ..... (9) 1030
Lage, H. ..... (10) 1131
Lakner, H. ..... (10) 1103, (10) 1221
Lam, Y.W. ..... (4) 387, (5) 470
Lambers, E.S. ..... (5) 429, (11) 1314
Lang, C.-I. ..... (8) 949
Lavoie, C. ..... (9) 1090
Le Beau, C. ..... (6) 476
Lee D.-G. ..... (11) 1365
Lee, C. ..... (5) 436
Lee, C.-D. ..... (9) 1053
Lee, C.-T. ..... (3) 262
Lee, H. ..... (8) 898
Lee, H.-D. ..... (2) L1
Lee, H.C. ..... (1) 37
Lee, H.C. ..... (6) 556, (6) 662
Lee, H.P. ..... (9) 1083
Lee, I.-S. ..... (12) 1394
Lee, J. ..... (6) 584
Lee, J.-W. ..... (10) 1199
Lee, J.W. .. (3) 290, (5) 429, (11) 1279, (11) 1303, (11) 1310, (11) 1314
Lee, K.J. ..... (4) 361
Lee, K.N. ..... (11) 1279
Lee, M.B. ..... (2) L1
Lee, M.H. ..... (6) 507
Lee, M.Y. ..... (2) L1
Lee, S.-M. ..... (2) 83
Lee, S.D. ..... (6) 552
Lee, S.H. ..... (10) 1244
Lee, S.H. ..... (6) 556
Lee, S.I. ..... (2) L1
Lee, S.R. ..... (9) 969, (9) 1048
Lee, T.S. ..... (6) 552
Lee, Z.Y. ..... (1) 21
Leem, J.H. ..... (6) 507
Legay, P. ..... (12) L32
Leonhardt, D. ..... (11) 1320
LeRoux, G. ..... (12) L32
Leung, K.M. ..... (4) 387, (5) 470
Lew, A.Y. ..... (2) 64
Li, C. ..... (2) 78
Li, J. ..... (1) 43
Li, J. ..... (4) 347
Li, J.C.M. ..... (7) 827, (7) 859
Li, L. ..... (10) 1189
Li, L. ..... (12) 1376, (12) 1382
Li, L. ..... (6) 756

Li, X. ..... (3) 306, (10) 1164
Li, Y. ..... (9) 1083
Liao, P.-K. ..... (6) 567
Liliental-Weber, Z. ..... (5) 449
Lin, C.-H. ..... (5) 440
Lin, C.H. ..... (1) 43, (8) 944
Lin, H.C. ..... (8) 889
Linden, K.J. ..... (10) 1145
Lindle, J.R. ..... (5) 440
Linh, N.T. ..... (1) 16
Linnarsson, M.K. ..... (3) 187
Liu, D.R. ..... (9) 1058
Liu, G. ..... (10) 1109
Liu, H.-Y. ..... (6) 567
Liu, H.C. (1) 43, (12) 1376, (12) 1382
Lombardi, L. ..... (5) 459
Look, D.C. ..... (12) L29
López-Villanueva, J.A. ..... (3) 203
Lossy, R. ..... (3) 123
Lothian, J.R. ..... (11) 1287
Lozano-Tovar, P. ..... (2) 73
Lu, H. ..... (3) 281
Lu, T.-M. ..... (2) 78, (4) 397, (8) 949
Lu, Y. ..... (7) 852
Lu, Y.-C. ..... (3) 243
Lund, J.C. ..... (6) 529
Luo, Y.Y. ..... (6) 511
Lux, G.E. ..... (6) 588
Lyakhovitskaya, V. .... (2) 97, (8) 893
Lyu, Y.-T. ..... (3) 262
Lyubomirsky, I. ..... (2) 97, (8) 893

M

Ma, D.I. ..... (2) 90
MacDonald, R.I. ..... (12) L25
MacKenzie, J.D. .. (3) 290, (11) 1266, (11) 1287, (11) 1292
Madangarli, V. ..... (3) 212
Magnea, N. ..... (6) 667
Mahidhara, R.K. ..... (7) 839
Maier, M. ..... (10) 1127
Mainzer, N. ..... (6) 606
Makeshwar, K. ..... (3) 108
Malherbe, J.B. ..... (5) 463
Malin, J.I. ..... (1) 43, (12) 1376, (12) 1382
Malin, J.I. ..... (5) 440
Mangiaracina, A. ..... (11) 1331
Mao, D.H. ..... (6) 678
Maracas, G.N. ..... (12) 1409
Marchand, H. ..... (10) 1205
Marcinkevicius, S. ..... (5) 449
Marinova, Ts. ..... (3) 119
Marks, D.G. ..... (6) 765
Markum, A.D. ..... (6) 656
Marrian, C. ..... (2) 90
Martin, G. ..... (1) 30
Martin, K.P. ..... (3) 301
Mascarenhas, A. ..... (9) 1048
Massie, S. ..... (1) 30
Mastrovito, A. ..... (10) 1145
Masut, R.A. ..... (10) 1205
Matherson, K.J. ..... (6) 765
Mathur, D. ..... (8) 949
Matsunami, H. ..... (3) 160, (3) 165
Mattson, M.A. ..... (6) 578
Mavoori, H. ..... (7) 783
Mayo, W.E. ..... (3) 243
Mazumder, J. ..... (1) 43, (12) 1376
McCann, P.J. ..... (5) 444
McCarthy, M.I. ..... (11) 1335
McCormack, M. ..... (8) 954
McLevige, W.V. ..... (6) 649, (6) 656
McNaughton, W.P. ..... (5) 415
Mejia, J. ..... (12) 1422
Melendes, R. ..... (6) 649
Melloch, M.R. ..... (3) 107, (3) 208
Mendorf, C. ..... (10) 1103, (10) 1221
Meng, W.J. ..... (11) 1297
Merchant, H.D. ..... (7) 773, (7) 833
Merz, C. ..... (10) 1127
Meyer, J.R. .. (5) 440, (6) 578, (6) 584
Miao, X.S. ..... (1) 21, (4) 387
Michaelsen, C. .... (9) 1009, (11) 1370
Miller, J. ..... (12) 1376, (12) 1382
Min, S.-K. ..... (5) 436
Mino, C.C. ..... (8) 915
Mirecki Millunchick, J. ..... (9) 1048
Mishra, B. ..... (4) 376
Mishra, U.K. ..... (3) 325, (10) 1118
Mitchel, W.C. ..... (3) 113
Mitra, P. ..... (6) 482
Mitsuyu, T. ..... (3) 183
Miwa, S. ..... (2) 53, (6) 705
Miyamoto, Y. ..... (6) 616
Moffat, H.K. ..... (1) 37
Moison, J.M. ..... (5) L9
Moldovan, M. ..... (6) 732
Molnar, B. ..... (3) 334
Montano, P.A. ..... (6) 750
Monteil, Y. ..... (2) L6
Moon, Y.M. ..... (6) 584
Moore, J.A. ..... (8) 949
Moran, B. ..... (7) 783
Morikawa, K. ..... (5) 423
Morisawa, Y. ..... (1) 34
Morkoç, H. ..... (9) 1076
Moss, R.H. ..... (10) 1131
Motamedi, M.E. ..... (6) 649
Mott, D.B. ..... (3) 330
Moustakas, T.D. ..... (3) 285
Moy, A ..... (12) 1382
Mu, J. ..... (3) 311
Müller, J. ..... (10) 1256
Müller, P. ..... (7) 873
Mullin, J.B. ..... (6) 610
Murakami, M. ..... (4) 410
Murarka, S.P. ..... (8) 935
Murata, H. ..... (10) 1250
Murry, S.J. ..... (5) 440
Murty, K.L. ..... (7) 839
Musicant, B.L. ..... (6) 482
Muth, J.F. ..... (3) 325
Myers, T.H. .(6) 534, (6) 578, (6) 732

N

Nabet, B. ..... (4) 372
Nag, B.R. ..... (2) 70
Nakadaira, A. ..... (3) 320
Nakamura, F. ..... (10) 1164
Nakata, T. ..... (3) 165
Nannini, A. ..... (8) L17
Narayan, J. ..... (4) 350
Narayanan, S. ..... (12) 1422
Nauka, K. ..... (5) 463
Nayar, N. ..... (6) 649
Neirynck, J.M. ..... (8) 935
Nemirovsky, Y. ..... (6) 756
Neri, B. ..... (8) L17
Niebuhr, R. ..... (10) 1127
Nielsen, B. ..... (11) 1349
Nielsen, M. ..... (4) 397
Ninagawa, N. ..... (3) 178
Ning, Z.-Y. ..... (8) 910
Nishi, K. ..... (3) 183
Nishida, T. ..... (10) 1214
Noh, S.-K. ..... (2) 83
Noh, S.K. ..... (9) 1053
Nordell, N. ..... (3) 187
Novák, J. ..... (1) 7
Nucci, J.A. ..... (9) 996

O

O'Brien, P. ..... (10) 1174
O'Dette, P. ..... (6) 482
O'Steen, M.L. ..... (5) 444, (11) 1342
Obermeier, E. ..... (3) 123
Off, J. ..... (10) 1103
Ohtake, A. ..... (6) 705
Ohtani, Y. ..... (4) 410
Ohyama, H. ..... (3) 183
Okada, Y. ..... (5) 423
Oku, T. ..... (4) 410
Ono, N. ..... (4) 410
Osiński, M. ..... (3) 311
Oster, A. ..... (10) 1159
Ouvrier-Buffet, P. ..... (6) 738

P

Pacaud, Y. ..... (3) 137
Paglino, C. ..... (7) 873
Pan, J.N. ..... (3) 208
Pang, S.W. ..... (11) 1320, (12) 1401
Panunto, M.J. ..... (1) 11
Pao, Y-H. ..... (9) 1058
Parent, D.W. ..... (6) 697, (6) 710
Parikh, A. ..... (6) 524, (9) 1065
Park, B.L. ..... (2) L1
Park, C. ..... (9) 1053
Park, C.G. ..... (9) 1053
Park, D.-G. ..... (9) 1076
Park, H.-S. ..... (2) 83
Park, J.W. ..... (6) 584
Park, K.T. ..... (3) 232
Park, M.-H. ..... (1) 25
Park, M.J. ..... (6) 552
Park, S.K. ..... (5) 436
Park, S.W. ..... (3) 172
Park, W. ..... (6) 728
Park, Y.D. ..... (11) 1274, (11) 1310
Park, Y.W. ..... (2) L1
Partin, D.L. ..... (10) 1237
Pasko, J.G. ..... (6) 649, (6) 656
Pathangey, B. ..... (11) 1355
Patriarche, G. ..... (12) L32
Patten, E. ..... (6) 476
Paultre, J.-E. ..... (10) 1205
Pautrat, J.L. ..... (6) 667

Pavlidis, D. ..... (1) 1
Peake, G.M. ..... (10) 1134
Pearson, S.D. ..... (6) 524, (9) 1065
Pearton, S.J. (3) 198, (3) 290, (5) 429, (11) 1265, (11) 1266, (11) 1279, (11) 1287, (11) 1292, (11) 1303, (11) 1310, (11) 1314
Pécz, B. ..... (3) 119
Pei, S.S. ..... (5) 440
Pekarskaya, E. ..... (8) 893
Pennycook, S.J. ..... (9) 1039
Perlin, P. ..... (3) 311
Perry, W.G. ..... (3) 224
Pesant, J.C. ..... (1) 16
Peterson, J.M. ..... (6) 515
Petit, P. ..... (12) L32
Phillips, M.R. ..... (8) 922
Phillips, O.F. ..... (4) 366
Phillips, T.J. ..... (6) 643
Piekarski, B.H. ..... (1) 11
Ping, A.T. ..... (3) 266
Pinizzotto, R.F. ..... (7) 883
Pinnington, T. ..... (12) L25
Polyakov, A.Y. ..... (3) 237
Popelar, C.H. ..... (7) 798
Post, G. ..... (12) L32
Power, Ch. ..... (12) 1428
Puchi, E.S. ..... (9) 980
Puga-Lambers, M. ..... (11) 1361

Q

Qi, H. ..... (10) 1189
Quillec, M. ..... (12) L32
Quintero, M. ..... (12) 1428

R

Rabinal, M.K. ..... (8) 893
Rack , P.D. ..... (11) 1355
Radefeld, A. ..... (10) 1103
Rajan, K. ..... (11) 1270
Rajavel, R.D. ..... (6) 476, (6) 488
Ramer, J.C. ..... (10) 1109
Rao, J.M. ..... (7) 798
Rao, M.V. ..... (3) 144, (3) 334
Rebbert, M.L. ..... (2) 90
Redaelli, G. ..... (5) 459
Reichert, W. ..... (3) 123
Reine, M.B. ..... (6) 482
Reinhardt, F. ..... (10) 1194
Ren, F. ..... (3) 198, (3) 290, (5) 429, (11) 1287, (11) 1303, (11) 1314
Ren, S.Y. ..... (4) 341
Ren, Z.-X. ..... (8) 910
Reno, R.C. ..... (1) 11
Renucci, M. ..... (3) 294
Rhiger, D.R. ..... (6) 515
Richards-Babb, M.R. (6) 534, (6) 578
Richman, R.H. ..... (5) 415
Richter, H.J. ..... (6) 542
Richter, W. ..... (10) 1159
Rickman, J.M. .... (9) 1009, (11) 1370
Ring, W.S. ..... (10) 1131
Rivero, A. ..... (12) 1428
Robinson, H.G. ..... (6) 600, (6) 629, (6) 678
Robinson, J. ..... (6) 697, (6) 710
Rodbell, K.P. ..... (9) 1090
Roe, K. ..... (12) 1371
Roh, S.D. ..... (3) 306
Rohatgi, A. ..... (12) 1422
Roldán, J.B. ..... (3) 203
Romano, L.T. ..... (3) 285
Rosbeck, J. ..... (6) 476
Rosentreter, M.A. ..... (4) 383
Roth, E.G. ..... (3) 144, (11) 1349
Roth, M.D. ..... (3) 113
Roy, R.A. ..... (9) 1090, (11) 1270
Rozenak, P. ..... (7) 868
Rubin, L. ..... (11) 1361
Ruiz, J. ..... (12) 1428
Rumberg, A. ..... (10) 1159
Russell, G.J. ..... (8) 915
Ruzin, A. ..... (6) 756
Rymaszewski, E.J. ..... (4) 397

S

Sadwick, L.P. ..... (4) 355
Saigal, A. ..... (7) 847
Salagaj, T. ..... (3) 243
Salmer, G. ..... (1) 16
Santic, B. ..... (10) 1127
Sartori, P. ..... (3) 311
Sato, M. ..... (10) 1154
Schaake, H.F. ..... (6) 567
Schieber, M. ..... (6) 529
Schineller, B. ..... (10) 1221
Schlotter, P. ..... (10) 1127
Schmitz, A.C. ..... (3) 266
Schmitz, D. ..... (10) 1123
Schmutz, C.J. ..... (9) 980
Schneider, M.A. ..... (4) 383
Schoen, K.J. ..... (3) 193
Schoen, O. ..... (10) 1123
Scholz, F. ..... (10) 1103
Schön, S. ..... (6) 728
Schöner, A. ..... (3) 187
Schremer, A.T. ..... (10) 1199
Schurman, M.J. ..... (3) 243
Schwechel, K. ..... (4) 376
Sciortino, P.F., Jr. ..... (3) 290
Seaford, M. ..... (1) 30
Seelmann-Eggebert, M. ..... (6) 542
Sen, S. ..... (6) 488, (6) 515
Sengupta, D.K. ..... (1) 43, (12) 1376, (12) 1382
Seong, T.-Y. ..... (10) 1250
Setzler, S.D. ..... (6) 732
Shamamian, V.A. ..... (11) 1320
Shamsuzzoha, M. ..... (11) 1331
Shan, W. ..... (3) 224
Sharangpani, R. ..... (4) 402
Shealy, J.R. ..... (10) 1199
Shen, H. ..... (2) 78
Shen, J. ..... (12) 1417
Shen, M.-R. ..... (8) 910
Sheng, J. ..... (6) 588
Sher, A. ..... (6) 571, (6) 625, (6) 683
Sher, A. ..... (6) 606
Shih, H.D. ..... (6) 502
Shilo, D. ..... (6) 606
Shin, H. ..... (6) 556, (6) 662
Shin, M. ..... (3) 237
Shinozaki, D.M. ..... (7) 852
Shiralagi, K. ..... (12) 1417
Shmagin, I.K. ..... (3) 325
Shu, P.K. ..... (3) 330
Shui, X. ..... (8) 928
Si, W. ..... (3) 128, (3) 151
Sides, P.J. ..... (10) 1261
Sigmon, T.W. ..... (8) L13
Sin, K. ..... (8) 898
Singh, R. . (4) 350, (4) 402, (10) 1184, (12) 1422
Singh, R. ..... (3) 285
Singh, R.K. ..... (11) 1265, (11) 1326, (11) 1365
Singh, V.V. ..... (9) 987
Sirtori, V. ..... (5) 459
Sivananthan, S. ..... (6) 561, (6) 621
Skauli, T. ..... (6) 688
Skorupa, W. ..... (3) 123, (3) 137
Skowronski, M. ..... (3) 237
Smith, D.J. ..... (12) 1389
Smith, S.R. ..... (3) 113
Sohmer, A. ..... (10) 1103
Song, B.K. ..... (6) 507, (6) 584
Song, J.J. ..... (3) 224
Song, W.S. ..... (6) 552
Song, Y. ..... (3) 212
Soulière, V. ..... (2) L6
Sprecher, A.F. ..... (7) 774
Srolovitz, D.J. ..... (9) 960
Stafford, A. ..... (6) 723
Staia, M.H. ..... (9) 980
Stall, R.A. (3) 217, (3) 243, (10) 1178
Starr, R. ..... (6) 482
Steckl, A.J. ..... (3) 217
Stillman, G.E. ..... (1) 43, (8) 944, (12) 1376, (12) 1382
Strecker, B.N. ..... (5) 444
Streetman, B.G. ..... (4) 391
Stringfellow, G.B. (4) 355, (10) 1244, (10) 1250
Stutz, C.E. ..... (7) 863
Sudarshan, T.S. ..... (3) 212
Sudharsanan, R. .. (6) 745, (10) 1145
Suehle, J.S. ..... (2) 90
Sugiyama, I. ..... (6) 616
Sullivan, J.P. ..... (9) 1021
Sumakeris, J. ..... (3) 151
Summers, C.J. ..... (6) 524, (6) 728, (9) 1065
Sun, S.-S. ..... (11) 1355
Sun, S.Z. ..... (10) 1134
Suzuki, T. ..... (3) 183
Svilan, V. ..... (9) 1090
Syllaios, A.J. ..... (6) 567

T

Takayama, N. ..... (1) 34
Takeuchi, M. ..... (1) 34
Tamargo, M.C. ..... (6) 511
Tan, H.H. ..... (5) 449
Tanaka, H. ..... (3) 320
Tanaka, K. ..... (6) 705
Tanaka, N. ..... (3) 160

Tansley, T.L. ..... (8) 922
Tarnowski, G.J. ..... (6) 635
Taylor, A.J. ..... (10) 1131
Taylor, P.C. ..... (7) 878
Tchounkeu, M. ..... (3) 294
Tennant, W.E. ..... (6) 649, (6) 656
Terry, F.L., Jr. . (12) 1401, (12) 1409
Thiery, J.F. ..... (1) 16
Thomas, S., III . (12) 1376, (12) 1401
Thompson, P. ..... (9) 1083
Thoms, B.D. ..... (11) 1320
Thothathiri, M. ..... (3) 281
Thrush, C.M. ..... (10) 1237
Thundat, T. ..... (9) 1039
Tian, Y.L. ..... (3) 144
Tiedje, T. ..... (12) L25
Tin, C.C. ..... (3) 212
Tomimasu, T. ..... (3) 183
Tong, W. ..... (6) 728
Tovar, R. ..... (12) 1428
Tran, C. ..... (3) 217
Triboulet, R. ..... (2) 97
Tröger, R.T. ..... (12) 1371
Trogolo, J. ..... (11) 1270
Tsai, C.-D. ..... (3) 262
Tsui, R. ..... (12)1417
Tsvetkov, V. ..... (3) 128
Tu, C.W. ..... (2) 64, (3) 252
Tucker, J. ..... (1) 30, (12) 1376, (12) 1382
Turnbull, D.A. ..... (1) 43, (3) 306
Turrell, B.G. ..... (2) 73
Twesten, R.D. ..... (9) 969, (9) 1048

U

Uchibori, C.J. ..... (4) 410
Ueda, T. ..... (8) 898
Ulbrich, R.G. ..... (4) 383

V

Vakerlis, G.D. ..... (6) 745
Van Scyoc, J.M. ..... (6) 529
van Hove, J. ..... (11) 1266, (11) 1292
van Schilfgaarde, M. (6) 625, (6) 683
Vartuli, C.B. ..... (11) 1287
Vaughan, M.R. ..... (8) 922
Vaynman, S. ..... (7) 783
Vedula, L. ..... (12) 1422
Venables, D. ..... (11) 1361
Venezia, V.C. ..... (11) 1349
Venkatraman, C. ..... (3) 193
Verger, L. ..... (6) 738
Vernon, S. ..... (10) 1145
Volckmann, E.H. ..... (8) 915
Vydyanath, H.R. ..... (6) 621

W

Wachtendorf, B. ..... (10) 1123
Wagner, B.K. ..... (6) 728, (9) 1065
Walck, S.D. ..... (4) 391
Walker, B. ..... (6) 488
Wang, C.A. ..... (10) 1231
Wang, H. ..... (8) 910
Wang, J. ..... (3) 232
Wang, K. ..... (1) 1
Wang, L. ..... (6) 588
Wang, L.C. ..... (1) 25
Wang, S.C. ..... (8) L21
Wang, Y.C. ..... (8) 944
Warddrip, M.L. (10) 1169, (10) 1189
Warmack, R.J. ..... (9) 1039
Warnick, S.C. ..... (10) 1145
Washburn, J. ..... (5) 449
Watkins, S.P. ..... (10) 1174
Waytena, G.L. ..... (2) 90
Webb, D.P. ..... (4) 387, (5) 470
Weiler, M.H. ..... (6) 482, (6) 635
Welstand, R.B. ..... (2) 64
Wenderoth, M. ..... (4) 383
Westphal, G. ..... (6) 567
Weyers, M. ..... (10) 1154, (10) 1159
Wickenden, A.E. ..... (3) 334
Wickenden, D.K. ..... (3) 330
Wijewarnasuriya, P.S. ..... (6) 621
Wilkerson, K.J. ..... (10) 1169
Williams, B.L. ..... (6) 600, (6) 629
Wilson, J.A. ..... (6) 476
Wilson, R.G. ..... (3) 198, (3) 237, (11) 1287, (12) 1371
Woelk, E. ..... (10) 1123
Woitok, J. ..... (10) 1156
Wong, C.K.H. ..... (4) 387, (5) 470
Woodall, J.M. ..... (3) 198
Woolfenden, J.M. ..... (6) 765
Wu, O.K. ..... (6) 476, (6) 488
Wu, P.K. ..... (8) 949
Wu, W. ... (1) 30, (12) 1376, (12) 1382
Wu, Z. ..... (3) 281

X

Xu, J. ..... (10) 1256

Y

Yablonskii, G.P ..... (10) 1256
Yakimova, R. ..... (3) 119
Yalisov, S.M. ..... (9) 959
Yan, C.H. ..... (2) 64
Yang, F. ..... (7) 859
Yang, G.-R. ... (2) 78, (4) 397, (8) 935, (8) 949
Yang, J.W. ..... (3) 266
Yang, R.Q. ..... (5) 440
Yang, T. ..... (6) 728
Yang, Y.D. ..... (8) L21
Yao, T. ..... (2) 53, (3) 232, (5) 423, (6) 705
Yasuda, T. ..... (2) 53, (6) 705
Yasui, K. ..... (3) 178
Ye, C. ..... (8) 910
Yeh, M.-Y. ..... (3) 262
Yeo, P. ..... (10) 1174
Yip, R.Y.-F. ..... (10) 1205
Yong, K. ..... (10) 1261
Yoo, K.-H. ..... (6) 584
Yoo, S.S. ..... (6) 750
Yoon, E. ..... (10) 1164
Yoon, H. ..... (6) 529
You, L. ..... (8) 949
Youn, C.-J. ..... (12) 1394
Young, E.T. ..... (6) 765
Youtz, A.E. ..... (4) 372
Yu, E.T. ..... (2) 64
Yu, P.K.L. ..... (2) 64
Yu, Z. ..... (6) 534, (6) 732
Yu, Z.J. ..... (12) 1389
Yuri, M. ..... (8) 898

Z

Zandian, M. (6) 493, (6) 621, (6) 649, (6) 656
Zappone, W. ..... (6) 710
Zhang, D. ..... (5) 440
Zhang, L.H. ..... (6) 524
Zhang, S. ..... (7) 859
Zhang, X.G. ..... (6) 697, (6) 710
Zhang, Y. ..... (9) 1048
Zhao, G. ..... (6) 697, (6) 710
Zhao, Y.-P. ..... (8) 935
Zheleva, T. ..... (3) 224
Zhmurkin, D.V. ..... (7) 791
Zhou, J.J. ..... (9) 1083
Zhu, J.T. ..... (2) 64
Zhu, N. ..... (6) 600
Zhu, Z. ..... (3) 232, (5) 423
Zimmerman, M.A. ..... (7) 847
Zimmermann, H. ..... (6) 542
Zogg, H. ..... (7) 873
Zolotoyabko, E. ..... (6) 606
Zubia, D. ..... (10) 1109
Zuo, H.Y. ..... (8) 922

(111)B ..... (10) 1214
(311)A ..... (10) 1140
1/f noise ..... (6) 643
3C-SiC ..... (3) 151, (3) 183
4H-SiC ..... (3) 151
4.2K photoluminescence ..... (12) L29
6H-SiC ..... (3) 128, (3) 137, (3) 212, (4) 341
II-IV semiconductors ..... (6) 723, (6) 534
III-N materials ..... (11) 1266
III-nitrides ..... (10) 1123
III-V semiconductors ..... (5) 429, (11) 1314
IV-VI semiconductors ..... (5) 444
V/III ratio ..... (3) 243

A

absorption coefficient ..... (6) 567, (6) 571
activation ..... (3) 183
activation energy ..... (7) 883
adhesion ..... (2) 78, (9) 980
admittance spectroscopy ..... (3) 113
AFM roughness ..... (10) 1098
afterglow plasma ..... (3) 178
Al/Nd-GaN ohmic contacts ... (3) 262
Al/Ni/Al/4H-SiC ..... (3) 119
Al/Si/Cu ..... (9) 1070
AlGaAs ..... (1) 37, (10) 1145
AlGaAsSb ..... (10) 1231
AlGaInAs lasers ..... (5) L9
AlGaP ..... (11) 1303
AlInAs ..... (12) L32
AlInP/GaAs ..... (8) 944
alkyl ligand exchange reactions ..... (10) 1169
AlN ..... (3) 212
AlN buffer layer ..... (8) 898
AlN film ..... (1) 21, (4) 387
alpha particle mapping ..... (6) 529
AlSiN film ..... (1) 21
aluminum ..... (3) 187, (9) 987
amorphization ..... (11) 1361
amorphous carbon ..... (9) 1021
amorphous silicon carbide (a-SiC) ..... (3) 183
amphoteric dopants ..... (6) 625
annealing ..... (3) 334, (11) 1279, (11) 1283
antimonides ..... (10) 1231
Ar ion laser ..... (5) 436
argon pressure ..... (4) 376
Arrhenius equation ..... (7) 847
arsenic doping ..... (6) 621
arsenide ..... (11) 1342
As precipitate ..... (9) 1053
atomic force microscope ..... (7) 791
atomic force microscopy (AFM) ..... (3) 272, (5) L9, (6) 556, (8) 935, (10) 1118
atomic hydrogen ..... (6) 534
atomic layer epitaxy (ALE) ..... (10) 1174
atomic nitrogen ..... (11) 1266
Au coating ..... (8) L21
Auger rate ..... (6) 571
avalanche photodetectors ..... (6) 488

B

BaF_2 ..... (5) 444
band alignment ..... (8) 922
band offset ..... (8) 944
band structure ..... (6) 571
bandgap ..... (2) 70
beam vibration theory ..... (9) 1002
benzimidazole ..... (5) 459
beryllium ..... (1) 16
$Bi_{0.88}Si_{0.12}$ ..... (8) 915
biaxial strain ..... (3) 224
blue emitters ..... (10) 1123
blue-green laser diodes ..... (6) 697
blue-green lasers ..... (6) 710
BN ..... (3) 237
boron ..... (3) 187
BPE ..... (4) 355
buffer layer ..... (7) 873
Burstein-Moss shift ..... (6) 678

C

C-V profile ..... (7) 863
$CaCO_3$ ..... (11) 1335
cadmium telluride ..... (10) 1261
cadmium zinc telluride ..... (6) 529
CaF_2 ..... (5) 444, (7) 873
capacitance-voltage (C-V) profiling ..... (2) L6
capitance-voltage (C-V) ..... (3) 212
carbon ..... (8) 928, (12) 1371
carbon doping ..... (10) 1189
carbon tetrachloride ..... (10) 1189
carbonization ..... (3) 217
carrier thermalization ..... (7) 878
cathodoluminescence (CL) ..... (3) 257, (3) 306
cathodoluminescence imaging ..... (3) 306
CdMnTe thin films ..... (2) 73
CdTe ..... (6) 507, (6) 511, (6) 534, (6) 610, (6) 750, (6) 765, (9) 1065
CdTe detectors ..... (6) 738
$CdTe/Hg_{1-x}Cd_xTe$ ..... (6) 606
CdTe/HgCdTe ..... (6) 556
CdZnTe ..... (6) 552, (6) 567, (6) 745, (6) 750, (6) 756, (6) 765, (10) 1169
CdZnTe detectors ..... (6) 738
CdZnTe substrate cleaning .. (6) 542
CdZnTe substrates ..... (6) 515
ceramic ball grid array (CBGA) ..... (7) 814
ceramic thin films ..... (11) 1297
chamber configuration ..... (4) 376
characterization ..... (3) 217
chemical beam epitaxy (CBE) ..... (4) 355, (12) 1417
chemical diffusion ..... (7) 839
chemical oxidation of HgCdTe ..... (6) 556
chemical vapor deposition (CVD) ..... (3) 232, (8) 949, (9) 960, (9) 980, (12) 1389
chemical-mechanical polishing (CMP) ..... (8) 935
chlorofluorcarbon (CFC) alternative ..... (5) 436
clustering ..... (1) 30
Co-Si-C ternary phase diagram ..... (3) 172
Co/SiC interface reaction ..... (3) 172
coarsening ..... (7) 774
coating ..... (9) 980
compensation ..... (3) 243
composition ..... (10) 1154
composition analysis ..... (6) 588
composition modulation ..... (9) 1048
computer simulation ..... (9) 960
condensation and re-evaporation coefficients ..... (6) 688
conduction band offset ..... (2) L6
constitutive modeling ..... (7) 783
contact resistance ..... (2) 90
contacts ..... (6) 756
convergent beam electron diffraction (CBED) ..... (10) 1103
coolers ..... (8) 915
copper ..... (7) 833, (8) L17, (9) 996
copper surface ..... (5) 459
crack propagation ..... (9) 1058
cracked area ..... (7) 774
creep ..... (7) 783, (7) 827, (7) 833, (7) 839, (7) 847, (7) 859
critical point parameters ..... (6) 561
critical thickness ..... (9) 966
cross-sectional scanning tunneling microscopy (XSTM) ..... (1) 30
cryogenic thermoelectric ..... (8) 915
crystal structure ..... (3) 285
crystallinity ..... (12) 1394
crystallization ..... (3) 183
crystallographic texture ..... (9) 1090
Cu ..... (2) 78
Cu-related trap ..... (12) L29
Cu_3Sn ..... (7) 883
Cu_6Sn_5 ..... (7) 883
$CuGaTe_2$ ..... (12) 1428
$CuInSe_2$ ..... (8) 893

D

dark current characteristics ... (1) 43
dc magnetron reactive sputtering ..... (4) 397
deep level transient spectroscopy (DLTS) ..... (5) 463
defect assisted tunneling ..... (4) 372
defect generation ..... (2) 53
defects ..... (3) 137, (4) 391, (5) 463, (6) 600, (6) 616, (6) 635
deformation mechanisms ..... (7) 839

degradation ..... (6) 715
depletion region ..... (6) 662
deposition rate ..... (12) 1394
detector arrays ..... (6) 482
diamond ..... (2) 90
diamond film(s) ..... (8) 910, (9) 960, (11) 1326, (11) 1365
dielectric constant ..... (8) 949
dielectric film ..... (8) 889
dielectric response temperature dependence ..... (12) 1409
dielectrics ..... (4) 350, (10) 1184
diffusion ..... (2) 97, (3) 123, (3) 187, (6) 610, (6) 616, (12) 1422
diffusion barrier ..... (2) L1, (4) 410
diffusion kinetics ..... (7) 883
diffusion limited ..... (6) 629
dimensional recovery ..... (7) 859
dimensional stability ..... (7) 859
dimethylethylamine alane (DMEAA) ..... (10) 1178
dimethylgermane ..... (3) 160
diode ..... (6) 635
diode lasers ..... (10) 1231
direct liquid injection ..... (4) 402
dislocation pipe diffusion ..... (7) 839
dislocation densities ..... (7) 873
dislocation dynamics ..... (7) 827
dislocation generation ..... (9) 1053
dislocation glide ..... (7) 839
dislocations ..... (3) 243, (6) 600, (7) 805, (12) 1417
dispersion strengthening ..... (1) 11
distributed feedback lasers ..... (10) 1131
donor bound excitons ..... (3) 224
dopant diffusion ..... (11) 1349
doping ..... (6) 625, (7) 878, (10) 1127, (10) 1154
doping memory ..... (3) 187
dose rate ..... (11) 1361
dry etching ..... (11) 1310
dual-band ..... (6) 482
dynamic mechanical test ..... (7) 852

E

EDMIn ..... (4) 355
effective 2D channels ..... (6) 584
elastic modulus ..... (9) 1002
electrical activation ..... (3) 208
electrical and optical behavior ..... (11) 1279
electrical and structural properties ..... (11) 1292
electrical conductivity ..... (9) 1021
electrical properties ..... (12) 1371, (12) 1394
electrodeposit ..... (7) 833
electroluminescence (EL) .... (6) 728, (11) 1355
electromagnetic interference shielding ..... (8) 928
electromigration ..... (2) 97, (9) 1070
electron cyclotron resonance (ECR) .... (5) 429, (6) 542, (11) 1303, (11) 1365
electron cyclotron resonance metalorganic molecular beam epitaxy (ECR MOMBE) .. (11) 1292
electron cyclotron resonance (ECR) plasma etching ..... (11) 1310
electron cyclotron resonance (ECR) plasma . (11) 1279, (11) 1326
electron cyclotron resonance-reactive ion etching (ECR-RIE) ..... (3) 290
electron effective mass ..... (6) 593
electron mobility ..... (3) 203, (6) 593, (10) 1237
electron paramagnetic resonance ..... (3) 137
electron temperature ..... (3) 178
electronic packaging ..... (7) 821
electronic properties ..... (11) 1274, (11) 1342
electrophotographic properties ..... (4) 387
ellipsometry ..... (4) 391, (12) 1409
end-of-range (EOR) defects ..... (11) 1349
energy gap ..... (12) 1428
entropy of fusion ..... (2) 70
epitaxial growth ..... (10) 1199
epitaxy ..... (3) 151, (3) 187, (10) 1237
etching ..... (3) 108, (3) 301, (5) 429, (6) 529
excimer laser ..... (8) L13

F

facets ..... (10) 1261
Faraday rotation ..... (6) 593
fast cycle processing ..... (12) 1422
feedback control ..... (10) 1145
Fermi level ..... (11) 1320
ferromagnetic thin films ... (11) 1274
fiber-optic superconducting quantum interference device (SQUID) magnetometry ..... (2) 73
fibers ..... (8) 928
filaments ..... (8) 928
film ..... (7) 798
finite element ..... (7) 814
fixed charge density ..... (6) 556
flat panel displays ..... (11) 1355
flexible manufacturing ..... (6) 629
flow modulation epitaxy ... (10) 1118
fluoropolymer films ..... (8) 941
flux ratio ..... (2) 53
focal plane array (FPA) ..... (6) 482
foil ..... (7) 833
free carrier absorption ..... (6) 593
free electron laser (FEL) ..... (3) 183

G

$Ga_{0.47}In_{0.53}As/InP$ ..... (2) L6
GaAs (001) ..... (10) 1189
GaAs ... (1) 16, (1) 37, (2) 64, (3) 320, (5) 436, (5) 449, (6) 507, (10) 1159, (10) 1164, (10) 1214, (12) 1409
GaAsN ..... (11) 1342
GaAsP ..... (10) 1159
GaBN ..... (3) 237
$GaCl_3$ ..... (8) 898
GaInAsP ..... (10) 1154
GaInAsSb ..... (10) 1231
GaInP ..... (10) 1199, (10) 1244, (10) 1250
GaInP/GaAs ..... (8) 944
gallium arsenide .. (7) 878, (10) 1174
gallium nitride (GaN) ..... (3) 224, (3) 257, (3) 306, (3) 311, (3) 334
gamma-ray ..... (6) 756
gamma-ray detector . (6) 745, (6) 750
gamma-ray imaging ..... (6) 765
GaN .. (1) 1, (3) 217, (3) 232, (3) 237, (3) 243, (3) 266, (3) 272, (3) 285, (3) 290, (3) 294, (3) 301, (3) 330, (4) 341, (10) 1114, (10) 1127, (11) 1266, (11) 1287, (11) 1342
GaN buffer layer ..... (10) 1098
GaN film ..... (8) 898
GaN/InGaN ..... (3) 325
GaP substrates ..... (10) 1199
gas source molecular beam epitaxy (GSMBE) .... (2) 64, (3) 160, (3) 252, (6) 728, (8) 944, (12) 1376, (12) 1382
Ge/Ni/ZnSe ..... (2) 83
$Ge_{1-y}C_y$ germanium ..... (12) 1371
gold ..... (9) 987
gold plating ..... (8) 893
grain boundary(ies) . (9) 987, (9) 996
grain boundary character distribution ..... (9) 987
grain boundary scattering .... (4) 383
grain engineering ..... (8) L13
grain size ..... (11) 1270
grain structure ..... (9) 1009
grain-boundary diffusion ..... (7) 839
grating layers ..... (10) 1131
gratings ..... (3) 290
grazing incidence x-ray reflectivity (GIXR) ..... (10) 1109
group IV alloys ..... (12) 1371
growth ..... (3) 294
growth rate estimation ..... (9) 1083
growth temperature ..... (11) 1292

H

Hall ..... (10) 1127
Hall effect ..... (3) 113
Hall measurement ..... (10) 1114
Hall mobility ..... (3) 243, (12) 1371
helium-ion etching ..... (5) 463
heteroepitaxy ..... (3) 160, (9) 969, (9) 1039
heterojunction ..... (6) 673
heterostructure ..... (6) 606
heterostructure insulated-gate field-effect transistor (HIGFET) ... (1) 16

heterostructure layer thickness calibration ..... (6) 588
heterostructures ..... (10) 1250
$Hg_{1-x}Cd_xTe$ ..... (6) 561
HgCdTe ..... (6) 482, (6) 488, (6) 493, (6) 502, (6) 515, (6) 524, (6) 534, (6) 552, (6) 571, (6) 588, (6) 600, (6) 616, (6) 621, (6) 625, (6) 629, (6) 635, (6) 643, (6) 649, (6) 656, (6) 662, (6) 667, (6) 673, (6) 678, (6) 688, (9) 1065
HgCdTe epitaxy ..... (6) 542
HgTe/CdTe superlattice ..... (6) 578, (6) 584
high aspect ratio ..... (5) 436
high field transport properties ..... (3) 203
high power radio frequency plasma ..... (3) 232
high pressure Bridgman ..... (6) 750
high resolution transmission electron microscopy (HRTEM) ..... (12) 1389
high resolution x-ray diffraction ..... (6) 529
high speed etching ..... (5) 436
high temperature contacts ... (3) 193
high temperature growth ..... (3) 320
high-electric field breakdown ..... (3) 212
high-purity AlGaAs ..... (10) 1178
high-speed devices ..... (12) L25
high-T_c superconductors ..... (8) 915
hollow-core screw dislocations ..... (3) 128
hopping conduction ..... (3) 113
hot-implantation ..... (3) 165
HPB-CdZnTe ..... (6) 745
hybrid gamma-ray detectors (6) 765
hydride vapor phase epitaxy (HVPE) ..... (8) 898
hydrocarbon radicals ..... (3) 160
hydrogen ..... (3) 198
hygrothermal ..... (7) 798
hysteresis capacitance-voltage (C-V) curve ..... (6) 556

I

IBr/Ar plasma ..... (11) 1303
ICl/Ar and IBr/Ar plasmas ..... (11) 1314
implant temperature ..... (11) 1361
implantation ..... (1) 16, (3) 144, (6) 606, (11) 1349
impression recovery ..... (7) 859
impression test ..... (7) 827
impurities ..... (3) 243
in-situ control ..... (6) 502
in-situ monitoring ..... (9) 1083 (10) 1154, (10) 1159
in-situ patterning ..... (6) 511
InAlAs ..... (4) 361
InAlN ..... (11) 1287
InAlP ..... (4) 361
InAsSb ..... (8) 903, (10) 1225
InAsSb/InTlSb ..... (4) 347
indentation recovery ..... (7) 859
indium arsenide ..... (10) 1205
indium gallium nitride (InGaN) ..... (10) 1118
indium gallium nitride ($In_xGa_{1-x}N$) ..... (3) 281
indium phosphide ..... (10) 1205
inductively coupled plasma (ICP) ..... (11) 1297
infrared (IR) detectors ..... (6) 502
infrared applications ..... (6) 571
infrared detectors ..... (6) 476
infrared focal plane arrays ... (6) 629
infrared optoelectronic devices ..... (6) 667
infrared spectroscopy ..... (10) 1169
InGaAs ..... (1) 37, (10) 1145, (10) 1164, (10) 1169
InGaAs/GaAs ..... (8) 922
InGaAs/InAlAs ..... (1) 30
InGaAs/InP ..... (2) 64, (12) 1382
InGaN ..... (3) 290, (10) 1103
InGaN quantum wells ..... (10) 1109
InGaP ..... (1) 7, (11) 1303
inhibitor ..... (5) 459
InN ..... (11) 1292
InNP ..... (3) 252
InP ..... (1) 25, (4) 355, (10) 1154, (11) 1283
InP heterojunction bipolar transistor (HBT) ..... (12) 1401
InP wafers ..... (1) 34
InP/InGaAs ..... (12) 1376
InPSb ..... (10) 1221
inter-layer subband mixing .. (6) 584
interconnections ..... (8) L17
interconnects ..... (7) 791
interdiffusion ..... (3) 262
interface chemistry ..... (2) 53
interface layer ..... (10) 1159
interface modification ..... (3) 160
interface roughening ..... (9) 1039
interface stress ..... (9) 966
interfaces ..... (9) 1076, (12) 1417
interfacial sliding ..... (7) 827
intermetallic growth ..... (7) 883
intermetallics ..... (1) 11
Invar material ..... (8) L21
$In_xGa_{1-x}As$ ..... (4) 410
iodine ..... (9) 1065
ion beam deposition ..... (11) 1270
ion bombardment ..... (9) 1030
ion damage ..... (11) 1279
ion energy ..... (11) 1297
ion implant ..... (6) 678
ion implantation ..... (3) 123, (3) 134, (3) 137, (3) 208, (3) 334, (5) 449, (6) 600, (6) 629, (11) 1361
ion scattering ..... (9) 1030
ion-driven surface chemistry ..... (11) 1320
IR detector materials ..... (6) 593
IR detectors ..... (6) 649, (6) 683
islanding ..... (9) 969
isoelectronic ..... (11) 1335
isostructural crystals ..... (11) 1335
I-V characteristics ..... (12) 1371

K

k · p approach ..... (6) 673
k · p calculation ..... (6) 578
Kerr effect enhancement ..... (1) 21

L

laser annealing ..... (3) 183
laser diodes ..... (5) 440
laser recrystallization ..... (8) L13
laser reflectance ..... (9) 1083
laser welding ..... (8) L21
laser-induced etching ..... (5) 436
lasers ..... (8) 903
lateral collection ..... (6) 635
lateral modulation ..... (9) 1048
lattice mismatch ..... (1) 1, (6) 515
lattice strain ..... (11) 1283
lead-free ..... (7) 839, (8) 954
lead-zirconate-titanate (PZT) ..... (11) 1331
leakage current ..... (11) 1287
LiF ..... (7) 827
light-emitting diodes ..... (3) 311
linear array ..... (6) 750
liquid crystalline polymer .... (7) 847
local oxidation of silicon structure (LOCOS) ..... (3) 134
long wavelength infrared (LWIR) detector ..... (4) 347
long wavelength infrared (LWIR) ..... (6) 482
long wavelength infrared devices ..... (6) 542
low dielectric constant (K) interconnect dielectrics ..... (4) 402
low energy electron ..... (3) 301
low energy electron enhanced etching (LE4) ..... (3) 301
low p-type carrier concentration ..... (1) 37
low pressure metalorganic chemical vapor deposition (LP-MOCVD)(1) 7
low temperature (LT) GaAs . (4) 391
low temperature growth ..... (9) 1053
low temperature interdiffusion ..... (6) 578
low V/III molar ratio ..... (3) 320
low-pressure metalorganic chemical vapor deposition (MOCVD) ..... (3) 212
low-pressure metalorganic vapor phase epitaxy (MOVPE) ..... (2) 64, (3) 320
low-temperature-grown GaAs ..... (4) 372

M

magnetic thin films ..... (11) 1310
magnetization ..... (2) 73
magneto-optical ..... (6) 593
magnetotransport ..... (6) 584
magnetron sputtering ..... (11) 1297
maskless ..... (5) 436
mass production ..... (10) 1123
mass spectrometry surface passivation ..... (11) 1320
mass transpot ..... (10) 1131
mechanical properties ..... (7) 805, (8) 928, (8) 954
mechanical-chemical polishing ..... (1) 34
melting point ..... (2) 70
mercury cadmium telluride ..... (2) 97, (6) 600
metal-diamond-like-nano-composite ..... (3) 193
metal-insulator-semiconductor devices ..... (3) 212
metal-insulator-semiconductor (MIS) capacitors ..... (6) 552
metal-insulator-semiconductor (MIS) ..... (9) 1076
metal-semiconductor-metal (MSM) detectors ..... (4) 372
metallization ..... (2) 90, (9) 1070
metalorganic chemical vapor deposition (MOCVD) (1) 1, (3) 243, (3) 257, (3) 281, (3) 306, (4) 350, (4) 361, (6) 482, (8) 903, (10) 1109, (10) 1114, (10) 1118,(10) 1123, (10) 1127, (10) 1145, (10) 1164, (10) 1184, (10) 1199, (10) 1225,
metalorganic molecular beam epitaxy (MOMBE) ..... (6) 524, (11) 1266
metalorganic vapor phase expitaxy (MOVPE) ..... (3) 294, (6) 697, (6) 710, (6) 723, (10) 1140, (10) 1154, (10) 1159, (10) 1178, (10) 1214, (10) 1221, (10) 1256
microhardness ..... (4) 387
microindentation ..... (7) 852
microlens ..... (10) 1134
microlens array ..... (10) 1134
micropipes ..... (3) 128
microscratch test ..... (9) 980
microstructural control .... (11) 1326
microstructural metrics .... (11) 1270
microstructure ..... (8) 954, (9) 1009
microwave annealing ..... (3) 144
microwave modulation ..... (7) 878
microwave power ..... (11) 1314
mid wavelength infrared (MWIR) ..... (6) 482
mid-infrared ..... (5) 440, (8) 903, (10) 1231
mid-infrared lasers ..... (10) 1225
mid-infrared-emitters ..... (10) 1221
mid-wave detectors ..... (6) 476
minimum RBS channeling ... (8) 898
minority carrier lifetime ..... (6) 571
MIS capacitors ..... (6) 556
misoriented substrates ..... (3) 257
mobility ..... (3) 257
modeling ..... (6) 673, (7) 863
modulation-doped field-effect transistors (MODFETs) ..... (1) 30
moisture ..... (7) 798
molding compounds ..... (7) 821
molecular beam epitaxy (MBE) ..... (1) 30, (3) 272, (3) 285, (4) 391, (5) 423, (5) L9, (6) 476, (6) 488, (6) 493, (6) 502, (6) 507, (6) 511, (6) 534, (6) 578, (6) 621, (6) 649, (6) 656, (6) 667, (6) 688 (6) 705, (6) 732, (7) 863, (7) 868, (9) 1065, (9) 1083, (11) 1342, (12) 1371
Monte Carlo ..... (9) 960
morphology ..... (10) 1261
Mössbauer spectroscopy ..... (1) 11
multiple quantum well infrared photodetectors (QWIPs) ..... (1) 43
multiple quantum well(s) (MQWs) ..... (6) 715, (10) 1231

N

N plasma source ..... (3) 252
n^+-p junction ..... (3) 165
n-on-p ..... (6) 629
n-type doping ..... (6) 710
n-type GaAs ..... (4) 410
$NaNO_3$ ..... (11) 1335
nanopipes ..... (3) 243
narrow-gap ..... (6) 643
native oxide ..... (12) L32
negative ion ..... (11) 1355
neural networks ..... (6) 524
NH_3 ..... (8) 898
Ni/ZnSe ..... (2) 83
Ni_3Se_2 ..... (2) 83
nickel ..... (8) 928
nickel thin films ..... (11) 1270
NiFe ..... (11) 1310
NiFeCo ..... (11) 1310
NiMnSb ..... (11) 1274
niobium/aluminum ..... (9) 1009
nitridation ..... (10) 1098
nitride ..... (11) 1342
nitrogen doping ..... (6) 705
nitrogen plasma ..... (11) 1292
nitrogen surface ..... (11) 1287
nitrogen vacancy ..... (10) 1127
nitrogen-containing mixed group-V compounds ..... (3) 252
noise ..... (6) 756, (8) L17
non-equilibrium diodes ..... (6) 643
nondestructive testing ..... (6) 593
nonparabolic ..... (6) 678
nonplanar epitaxy ..... (10) 1194
nonplanar metalorganic vapor phase epitaxy (MOVPE) . (10) 1134
nonvolatile memory application ..... (11) 1331
nuclear medicine ..... (6) 765
nucleation density ..... (11) 1326

O

ohmic contact(s) ..... (2) 90, (4) 410, (6) 715, (8) 893
optical absorption ..... (12) 1428
optical constants ..... (10) 1145
optical emission spectroscopy ..... (12) 1401
optical interconnect ..... (10) 1134
optical properties . (6) 561, (12) 1409
optical pumping ..... (10) 1256
optoelectronic packaging ..... (8) L21
order ..... (10) 1244, (10) 1250
organic films ..... (4) 366
organic light emitting diodes (OLEDs) ..... (4) 366
organic photoconductor ..... (4) 387
organometallic ..... (10) 1237
organometallic vapor phase epitaxy (OMVPE).. (3) 224, (3) 237, (10) 1169, (10) 1189, (10) 1205, (10) 1231, (10) 1244, (10) 1250, (10) 1261
overgrowth ..... (10) 1131
oxidation ..... (3) 134
oxygen ..... (10) 1127

P

p-CdTe ..... (8) 893
p-GaAs ..... (11) 1279
P-I-N ..... (6) 745
p-InGaP ..... (11) 1279
p-n photodiodes ..... (6) 482
p-type doping ..... (6) 621
Parylene-F ..... (8) 949
parylene-N (PA-N) ..... (2) 78
parylene-N films ..... (8) 935
passivation ..... (3) 198, (12) L25
patterned growth ..... (6) 511
Pb-free solder ..... (7) 883
PbSe ..... (5) 444
PbSnSe ..... (7) 873
$PbTiO_3$ ..... (12) 1394
PC ..... (7) 859
Pd/Zn/Pd contact ..... (1) 25
peak-to-valley current ratio (PVCR) ..... (12) 1417
permanent-magnetic materials ..... (5) 415
phase diagrams ..... (6) 683
phase sequence ..... (3) 172
phase size ..... (7) 774
phosphors ..... (11) 1355
photo-assisted growth ..... (6) 723
photoassisted MOVPE ..... (6) 710
photoconductors ..... (3) 330
photocurrent ..... (6) 662
photodetectors ..... (12) L25
photodiode ..... (6) 678
photoeffects ..... (12) 1422
photoluminescence (PL) ..... (3) 217, (3) 224, (3) 257, (3) 281, (3) 294,

(3) 325, (6) 732, (7) 878, (8) 944, (10) 1118, (10) 1127, (10) 1164, (11) 1279
photoluminescence excitation (PLE) ..... (8) 944
photomagnetization ..... (2) 73
photostimulated desorption (PSD) ..... (11) 1335
physical vapor deposition . (11) 1297
planarization ..... (11) 1365
plasma enhanced chemical vapor desposition (PECVD).. (2) L1
plasma enhanced metalorganic chemical vapor deposition (PEMOCVD)..... (12) 1394
plasma etching ..... (6) 542, (11) 1287
plasma immersion ion implantation (PIII) ..... (2) 78
plasma partially ionized beam (plasma PIB) ..... (2) 78
plasma source ..... (6) 705
plasmas ..... (5) 429
plastic deformation kinetics . (7) 774
PMMA ..... (7) 859
point defects ..... (5) 449
Poisson's ratio ..... (3) 224
polar-optical phonon scattering ..... (3) 203
polishing ..... (6) 529
polycrystalline ..... (2) 73, (9) 1009
polyimide ..... (7) 791, (7) 798
polymer ..... (7) 859
polymer films ..... (7) 852
polymer-matrix composites .. (8) 928
polysilicon thin-film transistor (TFT)..... (8) L13
polystyrene ..... (7) 852
pre-amorphization ..... (11) 1349
process modeling ..... (6) 629
pseudomorphic high electron mobility transistor (p-HEMT) ..... (7) 863
pulse height correction method ..... (6) 738
pulsed laser deposition (PLD) ..... (11) 1331
PVD aluminum ..... (4) 376
pyrometric interferometry.. (9) 1083

Q

quantum efficiency ..... (1) 43
quantum well(s) (QWs)..... (2) L6, (3) 325, (5) 440, (10) 1103
quantum wires ..... (10) 1194
quantum-well infrared photodetectors ..... (12) 1376, (12) 1382
quasi-3D growth-direction energy dispersion ..... (6) 584

R

radiation detector(s) (6) 529, (6) 750
radio frequency sputtering... (4) 410
Raman spectroscopy ..... (3) 294
random telegraph noise (RTN) ..... (6) 616
rapid isothermal processing (RIP) .....(4) 350, (4) 402, (10) 1184
rapid thermal annealing (RTA) .....(1) 16, (1) 43, (12) 1394
rapid thermal processing (RTP) ..... (3) 144, (12) 1422
rare earth-transition metals (5) 415
ratcheting ..... (7) 814
reactive ion etching . (3) 266, (5) 429
reactive ion milling ..... (8) 941
reactive sputtering ..... (1) 21
readout multiplexer ..... (6) 765
rectifying-heterostructures .. (8) 910
red shift ..... (1) 43
reflectance anisotropy spectroscopy (RAS) ..... (10) 1154, (10) 1159
reflection high energy electron diffraction (RHEED) ..... (3) 272
refractive index ..... (8) 889
reliability ..... (8) L17
remote sensing ..... (6) 656
resistive Schottky detectors . (6) 756
resonant cavity ..... (6) 667
resonant interband tunneling diodes (RITDs) ..... (12) 1417
reverse leakage current ..... (3) 165
R_oA ..... (6) 662
roughening ..... (9) 969
Rutherford backscattering spectroscopy ..... (3) 334, (8) 898

S

sapphire substrate ..... (3) 237, (10) 1114
scanning electron microscopy (SEM) ..... (9) 1058
scanning tunneling microscopy (STM)..... (4) 383, (10) 1189
scanning tunneling potentiometry (STP)..... (4) 383
SCH laser ..... (10) 1256
Schottky ..... (3) 108
Schottky barrier contacts ..... (3) 193
Schottky barrier height ..... (2) 83
Schottky contacts ..... (4) 372
Schottky diode ..... (3) 266
secondary ion mass spectrometry (SIMS) ..... (2) 78, (6) 588, (6) 621, (11) 1283
selective etch ..... (12) 1401
selective growth ..... (10) 1214
selective-area epitaxy ..... (3) 306
self-assembled islands ..... (10) 1205
self-diffusion ..... (7) 839
self-limiting growth ..... (10) 1194
semi-insulating GaAs ..... (12) L29
semiconductor ..... (2) 70
semiconductor detector arrays ..... (6) 765
semiconductor materials .... (12) L25
semiconductor quantum dots ..... (10) 1199
semiconductor surfaces ..... (9) 1030
sensor ..... (10) 1237
shadow mask ..... (6) 511
shadow masked metalorganic vapor phase epitaxial growth (SMMG) ..... (10) 1134
shadow masked MOVPE growth ..... (10) 1134
shallow electrical junctions ..... (11) 1349
sheet charge ..... (1) 30
sheet resistance ..... (3) 165
Si ..... (7) 868
Si substrates ..... (7) 873
Si-C stretch mode ..... (3) 183
Si/AlGaAs interlayers..... (9) 1076
$Si_{1-x-y}Ge_xC_y$ ..... (12) 1371
SiC .....(3) 198, (3) 217, (3) 301
SiC/AlN ..... (12) 1389
SiGe .....(5) 463, (9) 969, (9) 1039
silicon ..... (3) 160, (12) 1422
silicon carbide ..... (3) 108, (3) 113, (3) 123, (3) 134, (3) 144, (3) 160, (3) 165, (3) 178, (3) 187, (3) 193, (3) 208
silicon carbide inversion layer ..... (3) 203
simulation ..... (6) 616
SiN/GaAs ..... (9) 1076
single crystal x-ray diffraction ..... (3) 281
slow surface state density .... (6) 556
Sn-Ag eutectic ..... (7) 783
Sn-Pb alloy ..... (7) 827
Sn-Zn eutectic ..... (7) 783
SOI ..... (3) 217
solder .....(1) 11, (7) 827, (7) 839, (8) 954
solder joint ..... (7) 814, (9) 1058
solders ..... (7) 783
specific contact resistance .... (3) 262
spectroscopic ellipsometry... (4) 366, (6) 502, (6) 561, (10) 1145
sputter deposition (5) 463, (11) 1355
sputtering ..... (11) 1274
SrS:Ce ..... (6) 728
stacking faults ..... (2) 53, (3) 243
STEM ..... (10) 1103
step coverage ..... (4) 376
stoichiometry ..... (4) 397
strain effects ..... (6) 507
strain relaxation .. (9) 969, (10) 1205
strained epitaxial films ..... (7) 868
strained quantum well(s) ..... (8) 922, (10) 1131
strained-layer superlattices ..... (10) 1225
stress dependence ..... (7) 847
stress exponent ..... (7) 774
stress relaxation ..... (7) 774, (7) 783, (7) 791, (7) 798, (7) 821, (7) 827, (7) 833, (9) 1021
structural defects ..... (6) 610
substrate ..... (4) 341

substrate misorientation .. (10) 1140
superlattice(s) ..... (4) 347, (9) 1048, (11) 1342
superplasticity ..... (7) 827
surface charge ..... (6) 678
surface cleaning ..... (6) 534
surface deoxidation ..... (5) L9
surface impedance ..... (8) 928
surface inversion channel .... (6) 635
surface morphology ..... (10) 1205, (11) 1314
surface passivation ..... (6) 552
surface photo-absorption . (10) 1164, (10) 1214
surface properties
morphology ..... (3) 262
surface recombination ..... (6) 635
surface segregation ..... (9) 969
surface steps ..... (10) 1244
surface stoichiometry ..... (2) 53
surface stress ..... (9) 966
surface treatment ..... (5) 423
synchrotron white beam x-ray topography (SWBXT) ..... (3) 151

T

Ta_2O_5 ..... (10) 1184
TaN ..... (11) 1310
tantalum oxide thin films ..... (4) 397
tantalum pentoxide ..... (8) 889
Te-rich phase boundary ..... (6) 688
temperature ..... (4) 376
tensile properties ..... (7) 839, (7) 847
tertiarybutylarsine (TBA) ..... (1) 37
texture ..... (9) 987, (9) 996
thallium ..... (6) 683
thallium alloys ..... (6) 571
thermal annealing ..... (4) 372
thermal cycle annealing ..... (1) 1
thermal deformation ..... (7) 791
thermal evolution ..... (9) 1021
thermal fatigue ..... (7) 814
thermal fatigue-creep ..... (9) 1058
thermal oxidation ..... (12) L32
thermal oxide ..... (3) 108
thermal stability ..... (11) 1283
thermally stimulated current spectroscopy ..... (12) L29
thermally stimulated current (5) 470
thermodynamic model ..... (6) 524
thermodynamic prediction of optimal growth temperature ..... (6) 688
thin film reactions ..... (9) 1009
thin film resistivity ..... (4) 383
thin film(s) ..... (6) 728, (7) 805, (9) 966, (9) 987, (9) 996, (9) 1002, (9) 1009, (11) 1355
three-band Kane ..... (8) 944
Ti diffusion ..... (2) 90
TiN ..... (9) 980
TiN coating ..... (11) 1297
$TiSi_2$ ..... (9) 1090
titanium/aluminum ..... (9) 1009
TPD ..... (10) 1189
transient-enchanced diffusion (TED) ..... (11) 1349
transmission electron microscopy (TEM) . (3) 119, (3) 224, (3) 285, (6) 600, (7) 868
transmission line model ..... (2) 90
trimethylgallium (TMG) ..... (3) 243
trimethylindium (TMIn) ..... (4) 361
trineopentylgallium ..... (10) 1174
triode plasma chemical vapor deposition (CVD) ..... (3) 178
trisdimethylaminoantimony ..... (10) 1237
tungsten ..... (3) 193
tungsten nitride ..... (2) L1, (4) 410
tunneling ..... (3) 311, (6) 678
twins ..... (3) 243
two-color detectors ..... (6) 476
two-dimensional nucleation ..... (10) 1214
type-II heterostructures ..... (5) 440

U

ultra large scale integration (ULSI) DRAM ..... (2) L1
ultra violet (UV) light assisted processing ..... (4) 402
ultraviolet (UV) detector ..... (3) 330
uncooled ..... (6) 643
Urbach rule ..... (6) 567
UV radiation ..... (5) 470

V

Vegard's rule ..... (6) 567
vertical-cavity surface-emitting laser (VCSEL) ..... (10) 1140
viscoelastic ..... (7) 798, (7) 852
viscoelastic properties ..... (7) 821
viscoplastic ..... (7) 814
void defects ..... (6) 524

X

x- and γ-ray applications ..... (6) 738
x-ray ..... (6) 756
x-ray detector ..... (6) 750
x-ray diffraction (XRD) ..... (3) 224, (3) 257, (6) 600, (6) 606, (7) 868, (9) 1090, (10) 1109, (10) 1114, (10) 1169
x-ray imager ..... (6) 738
x-ray photoelectron spectroscopy (XPS) ..... (2) 78, (3) 119, (4) 397, (5) 459, (8) 935
xerographic photoreceptor .... (5) 470
Xydar G930 ..... (7) 847

Y

yield strength ..... (7) 805

Z

Z-contrast ..... (10) 1103
zinc ..... (6) 610
zinc-blende GaN ..... (3) 320
Zn surface diffusion ..... (1) 25
Zn-doping ..... (1) 7
ZnMgSSe ..... (10) 1256
ZnSe ..... (2) 83, (6) 534, (6) 705, (6) 710, (6) 715, (6) 732
ZnSe homoepitaxy ..... (5) 423
ZnSe/GaAs ..... (2) 53
ZnSSe ..... (6) 697
$Zn_xCd_{1-x}Te$ ..... (6) 610